

National Symposium On Emerging Plasma Techniques for Materials
Processing and Industrial Applications 2014

Technical Programme

Day 1 (Thursday) Date 13/02/2014		
SESSION 1	Inauguration	
Time	Speaker	Chair
08.00-09.00 AM	Registration & Breakfast	
09.00 - 09.45AM	Inauguration	S. I. Patil (Head Dept. of Physics)
09.45 - 10.15 AM	Keynote Address by A. K. Das	
10.15 - 10.30 AM	Felicitation and Vote of Thanks	
10.30- 11.00 AM	HIGH TEA	
SESSION 2	Emerging Areas in Plasma Technology	
11.00 - 11.30 AM	P. I. John (Plasma Processing of Nanoparticles)	A. K. Das
11.30-12.00 Noon	S. V. Bhoraskar (Plasma Induced free Radicals and their Potential Applications in Biosciences)	
SESSION 3	Low Pressure Plasma Applications	
12.00 - 12.30 PM	D. S. Patil (Low Pressure Plasma Assisted Chemical Vapour Deposition)	M. A. More
12.30 - 01.00 PM	S. Mukherjee (Applications of Plasma Nitriding Process)	
01.00 -02.00 PM	LUNCH	
SESSION 4	Simulation and Design Development	
02.00 - 02.30 PM	K. Ramchandran (Modelling and simulation of Thermal Plasma Material Processing)	S. D. Dhole
02.30 - 03.00 PM	S. Ghorui (Role of Thermo-physical Properties on Design and Development of Thermal Plasma Devices)	
03.00 - 03.30 PM	A. K. Tak (Simulation of particle nucleation and growth in transferred arc thermal plasma system)	
03.30 - 04.00PM	TEA	
SESSION 4	Novel Plasma Applications	

04.00 - 04.30 PM	S. K. Nema (Biomedical Waste Disposal and Syn Gas Recovery from Petroleum Waste using Thermal Plasma Technology)	K. Ramchandran
04.30 - 05.00 PM	N. K. Joshi (Plasma emission spectroscopy)	
05.00 - 05.10 PM	Oral - Anurag Mishra	
05.10 - 05.20 PM	Oral - Rajnish Kumar	
05.20 - 05.30 PM	Oral - Pratima Mishra	
05.30 - 06.00 PM	SNACKS	
SESSION 5	Special Evening Lecture	
06.00 - 07.00 PM	N. Venkatramani (Plasma materials processing – A swot analysis)	S. Mukherjee
07.00- 08.30 PM	DINNER	

Day 2 (Friday) Date 14/02/2014		
Time	Speaker	Chair
08.30-09.30 AM	Breakfast	
SESSION 1	Basic Plasmas Sources and Diagnostics	
09.30 - 10.15 AM	Ashish Ganguli (Understanding Plasma Sources)	N. Venkatramani
10.15 - 10.45 AM	S. N. Sahasrabudhe	
10.45-11.15 AM	TEA	
SESSION 2	Emerging Applications	
11.15 – 11.30 AM	Mrs. Smrutiprava Das (Plasma parameters in the dielectric barrier discharge reactor)	P. V. Padmanabhan
11.30 – 11.45 AM	Varsha Raut (Metallic Nanopowders Synthesised by Transferred Arc Thermal Plasma Technique)	
11.45 – 12.00 Noon	Tejashree Bhawe (Dc Arc Plasma Assisted Synthesis Of Biocompatible Nanoparticle Drug Complexes For Inhibition Of Mycobacteria)	

12.00 – 12.15 PM	I. Banerjee (Thermal plasma induced synthesis of magnetic iron oxide nanoparticles for drug delivery applications)	
12.15 – 12.30 PM	Soumen Karmakar (Phenomenological perspectives of formation of few-layer graphene in carbon arcs)	
12.30 – 12.45 PM	Santosh Mahapatra (<i>Plasma Wake Field Acceleration</i>)	
12.45 – 01.00 PM	Ashok Nawale (Thermal plasma synthesis of Ni doped CoFe ₂ O ₄ magnetic nanoparticles and their characterizations)	
01.00-02.00 PM	LUNCH	
SESSION 3	Plasma Spray Processing; Special Purpose Coatings	
02.00 – 02.30 PM	PVA Padmanabhan (Plasma spraying: Principles and Applications)	
02.30 – 03.00 PM	V. L. Mathe (Magnetic nano-particle generation using thermal plasma reactor)	S. Jadkar
03.00 - 03.10 PM	Oral - Kavita Rathore	
03.10 - 3.20 PM	Oral - R. K. Kalal	K. P. Adhi
03.20 - 03.30 PM	Oral - Rajib Kar	
03.30 - 03.40 PM	Oral – Avinash Bansode	
03.40 -04.00 PM	TEA	
SESSION 4	Poster	
04.00 -06.00 PM	Poster	
06.00 -07.00 PM	Evening Lecture K. C. Mittal (Electron Beam And Its Applications)	D. S. Joag
07.00- 08.30 PM	DINNER	

Day 3 (Saturday) Date 15/02/2014		
Time	Lecturer	Chair
08.30-09.30 AM	Breakfast	
SESSION 1	Basics of Plasma	
09.30 - 10.00 AM	Shrikant Joshi	Mrs. Smrutiprava Das
10.00 - 10.30 AM	Ram Prakash (UV Excimer Plasma Sources For Industrial And Medical Applications)	
10.30 - 11.00 AM	Sathish Kumar Bandlamudi (Langmuir Probe Payload for Space Re-entry Missions)	
11.00-11.15 AM	TEA	
SESSION 2	Industrial Presentations	
11.15 - 11.30 AM	Aanand Bhandari	Tanay Seth
11.30 - 11.45 AM	Rajesh Bhide (Wear Resistance Coatings Using Plasma Assisted)	
11.45-12.00 Noon	Milind Acharaya (Physical Vapour Deposition Technology For Advance Surface Engineering Applications)	
12.00 - 12.10 PM	Oral - Vandana Chaturvedi	S. W. Gosavi
12.10 - 12.20 PM	Oral - A. Pragatheeswaran	
12.20 - 12.30 PM	Oral - Uttam Sharma	
12.30 - 12.40 PM	Oral - R. B. Tyata	
12.40 - 12.50 PM	Oral - Nilesh Kanhe	
12.50 - 01.00 PM	Oral - Chiti Tank	
01.00 - 2.00 PM	LUNCH	
SESSION 3		
02.00 - 03.00 PM	Valedictory	
03.00 -03.30 PM	TEA	